



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: *Baer et al.* ) Group No.: 1763  
Serial No.: 10/675,697 )  
Filed: 09/30/2003 ) Examiner: Arancibia  
  ) Docket No.: HSJ9-2003-0032US1

For: **"METHOD OF FORMING A READ SENSOR USING PHOTORESIST  
STRUCTURES WITHOUT UNDERCUTS WHICH ARE REMOVED  
USING CHEMICAL-MECHANICAL POLISHING (CMP) LIFT-OFF  
PROCESSES"**

DO  
NOT  
ENTER  
MOJO  
7/4/06

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

**AMENDMENT AND REQUEST FOR RECONSIDERATION**

The Applicants respectfully submit this Amendment And Request for Reconsideration for entry into the present application in response to the Office Action mailed on 21 March 2006.